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(71) Applicant:
SHIN-ETSU HANDOTAI COMPANY LIMITED
Chiyoda-ku Tokyo (JP)

(72) Inventors:
• **Fukami, Teruaki,**
C-304, Aza Ohhira 150-5
Nishishirakawa-gun, Fukushima-ken (JP)

• **Suzuki, Kiyoshi,**
Aza Uenohara 186
Nishishirakawa-gun, Fukushima-ken (JP)
• **Azito, Toshio,**
Azaue Uenohara 2
Nishishirakawa-gun, Fukushima-ken (JP)

(74) Representative:
Grünecker, Kinkeldey,
Stockmair & Schwanhäusser
Anwaltssozietät
Maximilianstrasse 58
80538 München (DE)

(54) Polishing apparatus and polishing method for silicon wafers

(57) A polishing apparatus and a polishing method of semiconductor wafers are provided, whereby heavy metal contamination of semiconductor wafers can be prevented effectively in a polishing process.

A polishing apparatus of semiconductor wafers including a turn table assembly having a rotatably fixed

turn table and a polishing slurry tank for storing polishing slurry to be supplied onto the turn table with a polishing slurry supplying member, wherein the polishing slurry supplying member is provided with means for eliminating heavy metal ions from the polishing slurry.

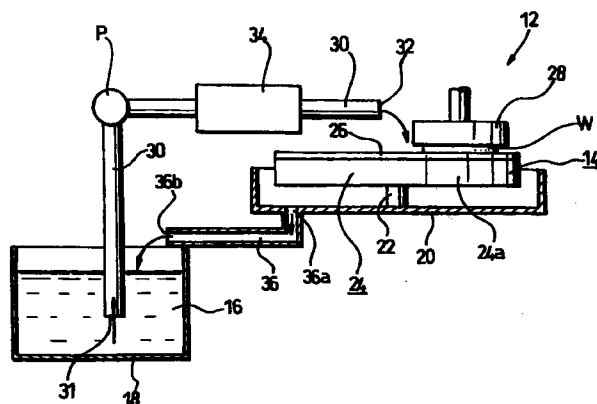


FIG. 1

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EUROPEAN SEARCH REPORT

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DOCUMENTS CONSIDERED TO BE RELEVANT			
Category	Citation of document with indication, where appropriate, of relevant passages	Relevant to claim	CLASSIFICATION OF THE APPLICATION (Int.Cl.6)
Y	PATENT ABSTRACTS OF JAPAN vol. 017, no. 102 (C-1031), 2 March 1993 & JP 04 293587 A (ASAHI CHEM IND CO LTD), 19 October 1992, * abstract *	1-3,6	B24B55/03 B24B37/04 C02F1/42 C02F1/62
Y	US 5 087 372 A (TOYOMOTO KAZUO ET AL) 11 February 1992 * column 4, line 30 - column 5, line 39 *	1-3,6	
A	EP 0 639 534 A (EBARA CORP) 22 February 1995 * page 2, column 2, line 18 - page 3, column 3, line 43 *	1,4,5	
A	PATENT ABSTRACTS OF JAPAN vol. 009, no. 045 (C-268), 26 February 1985 & JP 59 189987 A (NIPPON DENKI KK), 27 October 1984, * abstract *	1,6	
			TECHNICAL FIELDS SEARCHED (Int.Cl.6)
			B24B
The present search report has been drawn up for all claims			
Place of search		Date of completion of the search	Examiner
THE HAGUE		23 January 1998	Eschbach, D
CATEGORY OF CITED DOCUMENTS X : particularly relevant if taken alone Y : particularly relevant if combined with another document of the same category A : technological background O : non-written disclosure P : intermediate document T : theory or principle underlying the invention E : earlier patent document, but published on, or after the filing date D : document cited in the application L : document cited for other reasons & : member of the same patent family, corresponding document			

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